[English Translation of Excerpt from Reference 1]

Laid-Open Japanese Utility Model Application S63-036862 U

Laid Open Date: March 09, Year of Showa-63 (1988)

Title of Device: CAPILLARY PUMPLED LOOP

Japanese Utility Model Application S61-131724

Filing Date: August 28, Year of Showa-61 (1986)

Device Creator: Kiyoshi TANAKA [JP]

Applicant: NEC Corp. [JP]

[Claim]

A capillary pumped loop comprising an evaporator for introducing a working fluid from a working fluid inlet, heating the same for evaporation, and withdrawing vapor thereof from a vapor outlet, a condenser for introducing the vapor of said working fluid from a vapor inlet, cooling the same for condensation and withdrawing thus condensed working fluid from a working fluid outlet, a vapor line for providing communication between said working fluid outlet of said condenser and said working fluid inlet of said evaporator, wherein a no-return valve is disposed at said vapor outlet of said evaporator and at said vapor inlet of said condenser respectively along the direction to prevent the reverse flow of vapor.

[Brief Explanation of Figures]

Figure 1 is a conceptual figure showing the constitution of an example for the present device, and Figure 2 is a conceptual figure showing the constitution of a capillary pumped loop according to the prior art.

[Explanation of Codes]

(1a, 1b, 1c) No-return valve; (2a, 2b) Evaporator; (3a, 3b) Wick; (4) Vapor; (5) Working fluid; (6) Reservoir; (7) Separated vapor; (8) Condenser; (9) Vapor line; and (10) Liquid line.

⑩ 日 本 国 特 許 庁 (JP) ⑪実用新案出顧公開

⊕ 公開実用新案公報(U) 昭63-36862

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❸公開 昭和63年(1988) 3月9日

F 28 D 15/02

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7380-3L

審査請求 未請求 (全 頁)

❷考案の名称 キャピラリポンプループ

②実 顧 昭61-131724

❷出 顧 昭61(1986)8月28日

砂考 案 者

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明 細 書

- 3 考案の名称
 4 ャピラリポンプループ
- 2. 実用新案登録請求の範囲

配置

3. 考案の詳細な説明

(産業上の利用分野)

本考案は温度制御素子として用いられるキャピラリポンプループの改良に関する。

(従来の技術およびその問題点)

化アンモニアなどが用いられる。このように、蒸 発器 2 a , 2 b では吸熱が行われ、凝縮器 8 では 放熱が行われるから蒸発器を機器の内部に収め、 凝縮器を外部に置けば、熱を機器の内部から外部 へ放出できる。反対に、機器の内部に凝縮器を外 部に蒸発器を置けば外部から機器の内部へ熱を取 り込むことができる。第2図のように蒸発器を複 数個用いて構成したキャピラリポンプを機器の放 熱に使用すると、それぞれの蒸発器の周辺にある 機器の発熱量の差によって、各蒸発器間に温度差 が生じる。その温度差によって、各蒸発器間の蒸 気発生量および蒸気圧のバランスが失われ、蒸気 は圧力の高い蒸発器から低い蒸発器に向かって流 れ込む。蒸気が逆流するとその蒸発器においては 作動液の蒸発・吸熱のプロセスが定常状態から逸 脱しコントロールすることができなくなる。また、 このキャピラリポンプを人工衛星の温度制御素子 として用いると、打上げに伴う振動や衝撃あるい は宇宙空間の無重力などの影響で作動被5が凝縮 器8の蒸気取入れ口から蒸気流路9へ侵入するこ





とがある。すると蒸発器 2 a , 2 b 、液体流路 1 O 、凝縮器 8 中の作動被 5 には蒸気流路 9 に洩れ出した作動液 5 の体積分の真空の気泡が発生し液中に分散する。この気泡は水銀温度計の銀切れに相当するものであるが、このようなことが生じると蒸発器において作動液の循環が途切れてしまいキャピラリポンプが始動不能になる。

本考案の目的は、上に記したような欠点のない キャピラリポンプループを提供することにある。 (問題点を解決するための手段)

本考案のキャピラリポンプループは、第1図に示すように、作動液を作動液取入れ口から取取、充気を蒸気を蒸気を変える。 一般の では、 の で に の

ャピラリポンプループにおいて、前記蒸発器の前記蒸気取出し口と前記凝縮器の前記蒸気取入れ口にそれぞれ蒸気の逆流を防止する向きに蒸気の逆流を防止する向きに蒸気の逆流を防止する向きに逆止弁を設けたことを特徴とする。

(実施例)

第1図に本考案のキャピラリポンプループの一 実施例を示す。各蒸発器2a,2bの蒸気取出し 口と凝縮器8の蒸気取入れ口の蒸気流路9に逆止 弁1a,1b,1cを設けた。逆止弁はそれぞれ 矢印で示した蒸気の流れの逆流を防止する向まに 取り付けてある。従って、作動被5とその蒸気4 は順方向に循環し、どのような条件下でも逆流す ることはない。

(考案の効果)

このように、本考案のキャピラリポンプループは、複数個の蒸発器の間に蒸気圧のアンバランスが生じても蒸気の逆流は起こらないから蒸発器がコントロール不能に陥ることはない。また、人工衛星に搭載された場合でも作動液が蒸気相中へ洩



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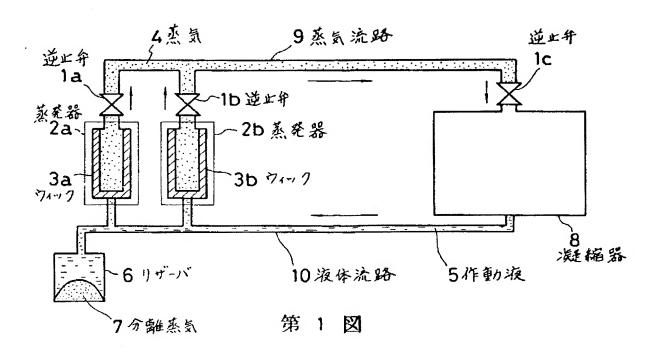
れ出さず従って作動被に気泡は発生しないから始 動不能になることはない。

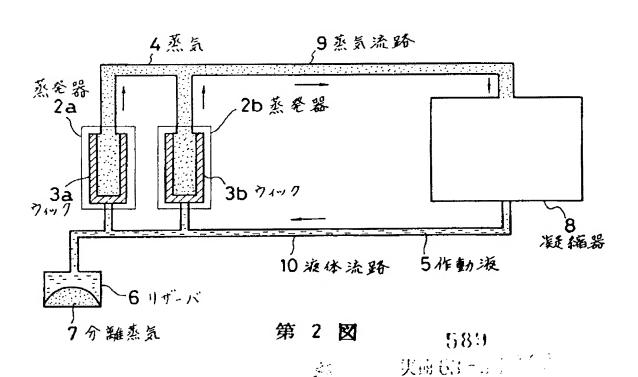
4. 図面の簡単な説明

第1図は本考案の一実施例の構成を示す概念図、 第2図は従来のキャピラリポンプループの構成を 示す概念図である。

1 a, 1 b, 1 c…逆止弁、2 a, 2 b…蒸発器、3 a, 3 b…ウィック、4…蒸気、5…作動液、6…リザーバ、7…分離蒸気、8…凝縮器、9…蒸気流路、10…液体流路。

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化四人命阻止 未 由 庙。春

手 続 補 正 書(自発)

62.2.23 昭和 年 月 日

特許庁長官殿

迴

1.事件の表示

昭和61年実用新案登録願第131724号

2. 考案の名称

キャピラリポンブルーブ

3.補正をする者

事件との関係

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5.補正の対象

明細書の考案の詳細な説明の欄

经

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実開 63-36 86 2 4

6.補正の内容

(1)明細書第2ページ第13行目から第16行目に、「吸熱効率が低下するので、作動液5の・・・・取除いている。」とあるのを、「吸熱効率が低下する。作動液5のタンクであるリザーバ6には気液分離機能を与えて、蒸発器2a,2bでの発熱変動および凝縮能力の変動があってもキャピラリポンプループ内の圧力を一定に保ち、飽和温度を一定に制御している。」と補正する。

(2)明細書第5ページ第3行目から第4行目に、「蒸気の逆流を防止する向きに蒸気の逆流を防止する向きに蒸気の逆流を防止する向きに逆止弁を設け」とあるのを、「蒸気の逆流を防止する向きに逆止弁を設け」と訂正する。

(19) Japanese Patent Office (JP)

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Examination Request: Not requested (Total of [blank] Pages) Sho 61[1986]-131724 (71) Applicant(s): **NEC** Corporation (21) Application No.: 33-1 5-Chome, Minato-ku, (22) Application Date: August 28, 1986 Tokyo-to Tanaka Kiyoshi (72) Inventor(s): **NEC** Corporation 33-1 5-Chome, Minato-ku, Tokyo-to (74) Agent: Shinsuke Honjo, Patent attorney

(54) CAPILLARY PUMP LOOP

[Amendment has been incorporated in the translation]

TITLE OF INVENTION

Capillary Pump Loop

CLAIM

Capillary pump loop, characterized in that the capillary pump loop comprises evaporators wherein an operating fluid is brought in from an operating fluid inlet, followed by heating to make it evaporate so that the vapor is let out from a vapor outlet; a condenser wherein the vapor of said operating fluid is brought in from the vapor outlet to be cooled and condensed, and the operating fluid condensed is let out from the operating fluid outlet; a vapor flow channel that connects said vapor outlet of said evaporator to said vapor inlet of said condenser; and an operating fluid flow channel that connects said operating fluid outlet of said condenser to said operating fluid inlet of said evaporator; with check valves being installed at said vapor outlet of said evaporator as well as at said vapor inlet of said condenser in the direction preventing backflow of the vapor.

DETAILED DESCRIPTION OF THE INVENTION

Field of Industrial Application

The present invention pertains to the improvement of a capillary pump loop used as temperature control device.

Prior Arts, and its Problems

The conventional capillary pump loop is configured as seen in Figure 2. Operating fluid 5 enters evaporators 2a, 2b to be heated and vaporized from wicks 3a and 3b. Vapor 4 goes to condenser 8 passing through vapor flow channel 9 to release its heat and undergoes condensation, and it returns to liquid. Operating fluid 5, which has returned to liquid, goes back to evaporators 2a and 2b through liquid flow channel 10. Endothermic efficiency of the evaporator will decrease if vapor became mixed in the operating fluid 5 that entered the evaporators 2a and 2b. A vapor-liquid separation function is provided to the reservoir 6, which is the tank for operating liquid 5. The pressure inside the capillary pump loop will be maintained at constant level and the saturated temperature will be controlled at constant level even if there is variation in heat generation as well as condensation capability. Following such circulation of the operating fluid 5 and its vapor 4, the heat is absorbed at evaporators 2a and 2b to vapor 4, and transferred to condenser 8 to be released here. Liquid freon or liquid ammonia that has large latent heat of vaporization is used as the operating fluid in order to create a large absorption of heat as well as heat generation. In this way, heat is absorbed at evaporators 2a and 2b, and

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released at condenser 8, so the heat can be released from inside the apparatus to the outside if the evaporator is housed inside the apparatus and the condenser is installed outside. On the contrary, installing the condenser inside the apparatus, and the evaporator outside, can capture the heat from outside into the inside of the apparatus. As can be seen in Figure 2, using the capillary pump built using several evaporators to release the heat at the apparatus generates temperature differences among evaporators according to the differences in the amount of heat generation of the apparatus present surrounding each evaporator. Depending on its temperature differences, the generation amount of vapor among the evaporators as well as the balance of the vapor pressure will be lost, and the vapor will flow from the evaporator with high pressure to the evaporator with low pressure. When the vapor back-flows, depending on its evaporator, the process of evaporating the operating fluid and absorbing the heat will deviate from the normal condition, and it can no longer be controlled. Moreover, when this capillary pump is used as the temperature control device of a satellite, the operating fluid 5 may invade from the vapor inlet of condenser 8 to the vapor flow channel 9 due to the influence of vibration or impact of the launch. This will generate vacuum bubbles from the bulk portion of the operating fluid 5 that was leaking at the vapor flow channel 9 in the operating fluid 5 at evaporator 2a and 2b, fluid flow channel 10, and condenser 8, and it will disperse in the liquid. These bubbles are equivalent to the silver leakage [sic, possibly referring to mercury leakage] of a mercury thermometer; however, if this type of symptom occurs, the circulation of the operating liquid in the evaporator will be discontinued, making the capillary pump unable to start.

The purpose of the present invention is to provide a capillary pump loop that does not have shortcomings mentioned above.

Means to solve the problems

The capillary pump loop of the present invention is characterized in that, as shown in Figure 1, the capillary pump loop comprises evaporators wherein an operating fluid is brought in from an operating fluid inlet, followed by heating to make it evaporate so that the vapor is let out from a vapor outlet; a condenser wherein the vapor of said operating fluid is brought in from the vapor outlet to be cooled and condensed, and the operating fluid condensed is let out from the operating fluid outlet; a vapor flow channel that connects said vapor outlet of said evaporator to said vapor inlet of said condenser; and an operating fluid flow channel that connects said operating fluid outlet of said condenser to said operating fluid inlet of said evaporator; with check valves being installed at said vapor outlet of said evaporator as well as at said vapor inlet of said condenser in the direction preventing backflow of the vapor.

Application Example

Figure 1 shows an application example of a capillary pump loop of the present invention. Check valves 1a, 1b, and 1c are provided at the vapor outlets of each evaporators 2a and 2b as well as at the vapor flow channel 9 of the vapor inlet of condenser 8. These check valves are installed in the direction preventing the backflow of the vapor as shown with the arrow in the

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figure. In this way, operating fluid 5 and its vapor 4 are circulated in the forward direction so that it will not backflow under any circumstances.

Effect of the Invention

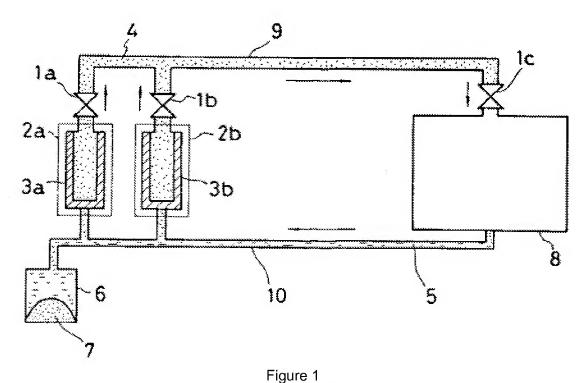
In this way, the capillary pump loop of the present invention does not incur a defect where it cannot be controlled because backflow of the vapor will not occur even when the imbalance of vapor pressure occurred among several evaporators. In addition, it will not fail to start because it will not generate bubbles in the operating fluid because the operating fluid does not leak into the vapor phase when it is installed in the satellite.

BRIEF EXPLANATION OF THE FIGURE

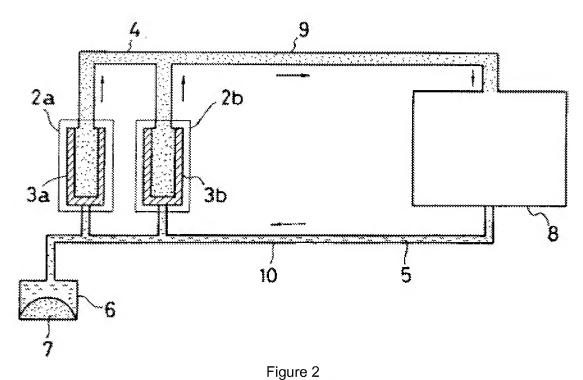
Figure 1 is an outline drawing showing the configuration of the application example of the present invention, and Figure 2 is an outline drawing showing the configuration of the conventional capillary pump loop.

1a, 1b, 1c ... check valves, 2a, 2b ... evaporators, 3a, 3b ... wicks, 4 ... vapor, 5 ... operating fluid, 6 .. reservoir, 7 ... separated vapor, 8 ... condenser, 9 ... vapor flow channel, 10 ... fluid flow channel.

Agent, Shinsuke Honjyo



1a, 1b, 1c ... check valves, 2a, 2b ... evaporators, 3a, 3b ... wicks, 4 ... vapor, 5 ... operating fluid, 6 .. reservoir, 7 ... separated vapor, 8 ... condenser, 9 ... vapor flow channel, 10 ... fluid flow channel.



1a, 1b, 1c ... check valves, 2a, 2b ... evaporators, 3a, 3b ... wicks, 4 ... vapor, 5 ... operating fluid, 6 .. reservoir, 7 ... separated vapor, 8 ... condenser, 9 ... vapor flow channel, 10 ... fluid flow channel.